

**UNCLASSIFIED**

**AD 408 418**

---

**DEFENSE DOCUMENTATION CENTER**

**FOR**

**SCIENTIFIC AND TECHNICAL INFORMATION**

**CAMERON STATION, ALEXANDRIA, VIRGINIA**



**UNCLASSIFIED**

NOTICE: When government or other drawings, specifications or other data are used for any purpose other than in connection with a definitely related government procurement operation, the U. S. Government thereby incurs no responsibility, nor any obligation whatsoever; and the fact that the Government may have formulated, furnished, or in any way supplied the said drawings, specifications, or other data is not to be regarded by implication or otherwise as in any manner licensing the holder or any other person or corporation, or conveying any rights or permission to manufacture, use or sell any patented invention that may in any way be related thereto.

AFCRL-63-155

*Technical Report 76*

**AN AUTOMATIC SYSTEM FOR MEASURING PLASMA PARAMETERS**

*Prepared for:*

AIR FORCE CAMBRIDGE RESEARCH LABORATORIES  
OFFICE OF AEROSPACE RESEARCH  
UNITED STATES AIR FORCE  
LAURENCE G. HANSCOM FIELD  
BEDFORD, MASSACHUSETTS

CONTRACT AF 19(628)-325  
PROJECT 4600  
TASK 460001

*By: W. E. Scharfman*

STANFORD RESEARCH INSTITUTE

MENLO PARK, CALIFORNIA

\*SRI

408 418

Requests for additional copies by Agencies of the Department of Defense, their contractors, and other Government agencies should be directed to the:

DEFENSE DOCUMENTATION CENTER (DDC)  
ARLINGTON HALL STATION  
ARLINGTON 12, VIRGINIA

Department of Defense contractors must be established for DDC services or have their 'need-to-know' certified by the cognizant military agency of their project or contract.

All other persons and organizations should apply to the:

U.S. DEPARTMENT OF COMMERCE  
OFFICE OF TECHNICAL SERVICES  
WASHINGTON 25, D.C.

STANFORD RESEARCH INSTITUTE

MENLO PARK, CALIFORNIA



May 1963

AFCRL-63-155

Technical Report 76

## AN AUTOMATIC SYSTEM FOR MEASURING PLASMA PARAMETERS

Prepared for:

AIR FORCE CAMBRIDGE RESEARCH LABORATORIES  
OFFICE OF AEROSPACE RESEARCH  
UNITED STATES AIR FORCE  
LAURENCE G. HANSCOM FIELD  
BEDFORD, MASSACHUSETTS

CONTRACT AF 19(628)-325  
PROJECT 4600  
TASK 460001

By: W. E. Scharfman

SRI Project No. 3977

Approved:

  
T. MORITA, MANAGER ELECTROMAGNETIC SCIENCES LABORATORY

  
D. R. SCHEUCH, DIRECTOR ELECTRONIC AND RADIO SCIENCES DIVISION

Copy No. 68

## ABSTRACT

---

An inexpensive system for automatic measurement of microwave phase shift is described. The system requires for its construction only components that would be required if a manual system were used, plus a servo loop. The phase is controlled by controlling the reflector voltage on a klystron, which in turn controls the microwave frequency.

A description is given of a prototype system that was constructed and tested. Measured results of phase shift as a function of control voltage and attenuation are presented.

## CONTENTS

---

ABSTRACT. . . . .	ii
LIST OF ILLUSTRATIONS . . . . .	iv
I INTRODUCTION . . . . .	1
II BRIDGE SYSTEM. . . . .	2
III EXPERIMENTAL RESULTS . . . . .	7

## ILLUSTRATIONS

---

Fig. 1(a)	Microwave System for Independent Measurement of Attenuation and Phase Shift. . . . .	2
Fig. 1(b)	Vector Diagram of Voltages at Output Terminals of the Magic Tee. . . . .	2
Fig. 2	Method of Introducing Control Voltage into the Klystron Reflector Voltage Circuit . . . . .	6
Fig. 3	Microwave System for Automatic Measurement of Attenuation and Phase Shift. . . . .	7
Fig. 4	Phase as a Function of Control Voltage for the Automatic System . . . . . ( $\Delta L = 3$ meters)	8
Fig. 5	Plot of Ratio of Plasma to Wave Frequency and Ratio of Collision to Wave Frequency as a Function of Normalized Attenuation in db/Radian and Normalized Phase Shift in Degrees/Radian . . .	9
Fig. 6	Automatic System Using ac Amplifiers . . . . .	10

## I INTRODUCTION

In order to determine the electron density and collision frequency of a plasma it is necessary to make two independent measurements. Very often this is performed by measuring the absorption and phase shift, at a single frequency, of an electromagnetic wave that is transmitted through the plasma. By constructing a bridge circuit in which the plasma is one arm and a calibrated phase shifter and calibrated attenuator are another arm, a sensitive instrument for measuring absorption and phase shift can be made. In this system, in order to null the bridge both the attenuator and the phase shifter must be adjusted. Both components must be adjusted before either the phase shift or attenuation of the plasma can be determined. The phase shift cannot be found independent of the attenuation.

In order to make such a system automatic, it would be necessary to have two servo loops, one controlling the attenuator and another controlling the phase shifter. An alternative system that does not require an adjustment of both components is described below. This system has the advantage that only one servo loop (on the phase shifter) is required. Further, in a low-collision plasma, the electron density can be found in terms of the phase shift alone. Thus, to determine the electron density, only the phase shift need be measured,

## II BRIDGE SYSTEM

The basic system is shown in Fig. 1(a). A klystron oscillator supplies microwave power which is divided in a directional coupler between a path that goes through the plasma (Path A) and a path that does

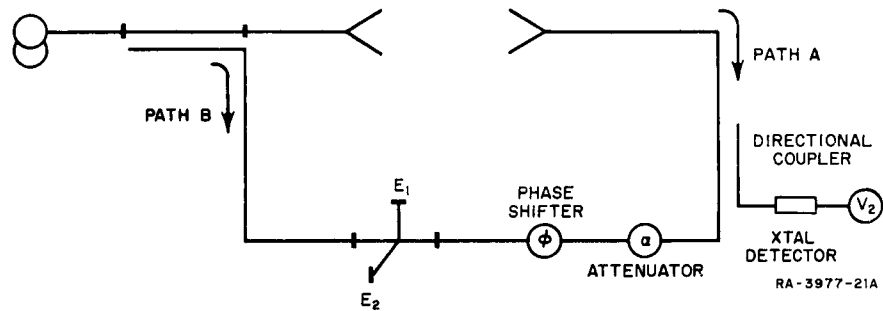
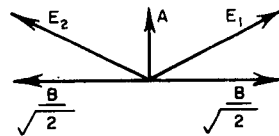


FIG. 1(a) MICROWAVE SYSTEM FOR INDEPENDENT MEASUREMENT OF ATTENUATION AND PHASE SHIFT

not (Path B). The two signals are recombined in a magic tee. As shown in Fig. 1(b), when the two signals are 90 degrees out of phase the resultant fields in the crossed arms of the magic tee,  $|E_1|$  and  $|E_2|$ , are



RA-3977-21

FIG. 1(b) VECTOR DIAGRAM OF VOLTAGES AT OUTPUT TERMINALS OF THE MAGIC TEE

equal. If the voltage difference between  $|E_1|$  and  $|E_2|$  is monitored, it will indicate when the input signals are in phase quadrature. When

a plasma changes the phase along Path A, the phase shifter is adjusted until  $|E_1| - |E_2| = 0$ . The change in the phase shifter is equal to the phase shift due to the plasma.

In this system the phase at which  $|E_1| = |E_2|$  is independent of the amplitude of the signals entering the magic tee along Paths A and B. Thus, phase shift can be measured independent of attenuation. Attenuation could be measured by monitoring the amplitude of the received signal by a directional coupler in the receiving arm.

There are several ways that a voltage-controllable phase shifter can be made. Ferrite phase shifters are commercially available, in which the phase shift is changed by varying the current in an electromagnet. However, this type of phase shifter has a hysteresis characteristic so that the phase shift is a multiple-valued function of the current. For a phase shifter with about 300 degrees of total phase shift the hysteresis error could amount to about 30 degrees. Thus for a given value of current the phase shift would be uncertain over a 30-degree range.

Traveling-wave-tube amplifiers have a phase-shift characteristic which is a function of the helix voltage. Thus a traveling-wave-tube amplifier can be used as a voltage-controllable phase shifter. The cost of such a device makes it unattractive.

Voltage-controlled crystal phase shifters have been designed and are commercially available in the lower microwave frequencies; however, the cost of these devices at X-band is still high, especially if a large phase shift is required.

A novel, inexpensive way of achieving a voltage-controllable phase shifter using only components that would be necessary for a manual system has been developed. Its operation is as follows. If a signal at frequency  $f_1$  propagates down a transmission line of length  $L_1$  with a wavelength of  $\lambda_{g1}$ , the total phase shift down the transmission line is  $2\pi/\lambda_{g1} L_1$ . The total phase shift down a length of line  $L_2$  is  $2\pi/\lambda_{g1} L_2$ . The difference in phase,  $\Delta \Phi$ , between the signals traveling down  $L_1$  and  $L_2$  is  $2\pi/\lambda_{g1} (L_1 - L_2)$ . If the frequency is changed, the guide wavelength,

and hence  $\Delta \Phi$ , changes. Thus, by changing the frequency the differential phase shift can be changed. If  $L_1 - L_2$  is many wavelengths long a small change in frequency will result in a large change in differential phase.

If  $L_1$  and  $L_2$  are the lengths of transmission line in Paths A and B, the phase difference between the signals from A and B at the magic tee will be

$$\Delta \Phi = \frac{2\pi}{\lambda_{g1}} (L_1 - L_2) + \Phi_c + \Phi_a$$

where  $\Phi_c$  = Phase-shifter setting

$\Phi_a$  = Phase shift across the transmission path between the antennas.

When  $\Phi_c$  is adjusted so that  $\Delta \Phi = 90^\circ$ ,  $|E_1| - |E_2| = 0$ . If a plasma changes  $\Phi_a$  so that  $\Delta \Phi$  is other than  $90^\circ$ , then  $\Delta \Phi$  can be made equal to  $90^\circ$  by changing the frequency.

The amount of phase shift for a given frequency change can be calculated as follows. The differential phase shift at the two frequencies is given by

$$\delta \Phi = 2\pi \left[ \frac{1}{\lambda_{g1}} - \frac{1}{\lambda_{g2}} \right] (L_1 - L_2)$$

For a  $TE_{01}$  mode in a rectangular waveguide, the guide wavelength is

$$\lambda_{g1} = \frac{1}{\sqrt{\left(\frac{f_1}{c}\right)^2 - \left(\frac{1}{2a}\right)^2}}$$

where

- $\lambda_{g1}$  = Guide wavelength
- $f_1$  = Frequency
- $c$  = Velocity of light
- $a$  = Waveguide width.

For small frequency changes, an approximate expression for the difference in wavelength may be found. Inserting this value in the expression for the differential phase we obtain

$$\delta \Phi = \frac{2\pi}{\lambda_{\Delta}} \frac{(L_1 - L_2)}{\sqrt{1 - \left(\frac{\lambda_1}{2a}\right)^2}}$$

where

$$\lambda_{\Delta} = \Delta f / c$$

$\Delta f$  = the change in frequency.

For example, a frequency change of 10 Mc at a frequency of 10 Gc will result in a phase change of 16.3 degrees/meter.

It is true that the plasma is dispersive so that the phase shift produced by it will also be frequency-dependent. However, the rate of change of phase constant through the plasma is of the same order as for a waveguide, so that if the plasma length is made much smaller than  $(L_1 - L_2)$ , the dispersive effect of the plasma will be negligible.

This method of obtaining a controllable phase shift could be used as follows. Assume the system is balanced before the plasma is introduced. Then, if the plasma introduces a phase change,  $E_1 \neq E_2$ . This voltage difference can serve as an error signal to drive a feedback amplifier, which in turn can be used to change the frequency. As the frequency changes,  $E_1 - E_2 \rightarrow 0$ . For sufficiently high loop gain,  $E_1 - E_2$  will be driven very close to zero.

The next question to consider is how to use this error signal to change the klystron frequency. The frequency can be changed by varying either the beam or reflector voltages. The reflector circuit draws practically zero current so that an external voltage applied in the reflector voltage line will not need to supply current. The reflector is several hundred volts above ground so that introducing the error signal into the circuit would raise the crystals to a high potential above ground, introducing dangerous voltages into the waveguide system.

This danger can be avoided by supplying the reflector voltage from a separate battery supply. The error signal can then be introduced at the ground side of the supply and thus be at low potential. The current drain on the batteries will be very small. The circuit is shown in Fig. 2.

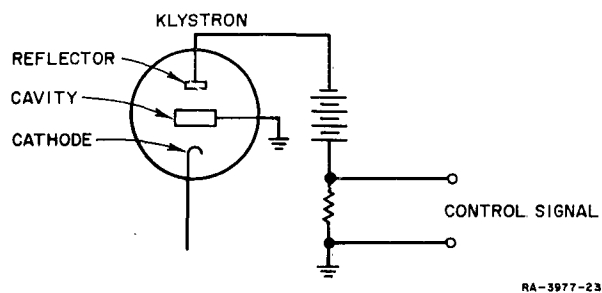
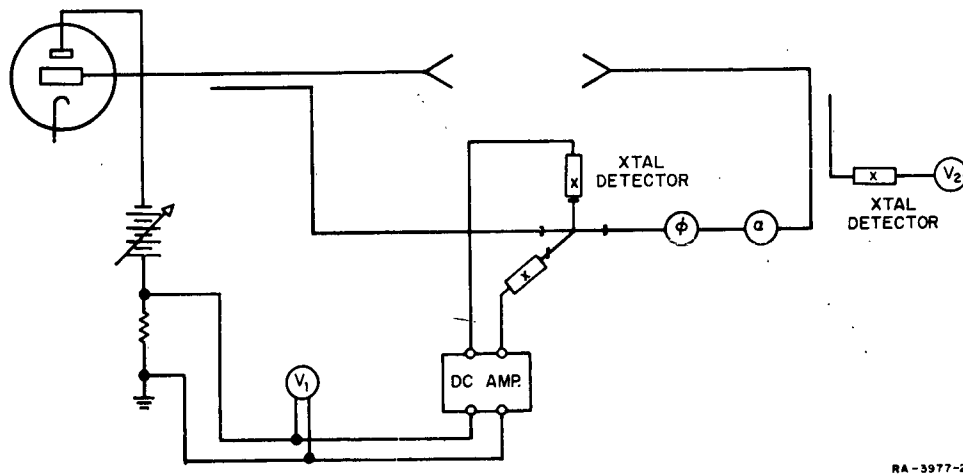


FIG. 2 METHOD OF INTRODUCING CONTROL VOLTAGE INTO THE KLYSTRON REFLECTOR VOLTAGE CIRCUIT

### III EXPERIMENTAL RESULT

A phase-measuring system working in this manner has been constructed and tested. The over-all system is shown in the schematic diagram of Fig. 3. The voltage out of the dc amplifier raises and lowers the total reflector voltage, thus changing the frequency. By measuring  $V_1$  as a function of  $\phi$ , the system can be calibrated in phase in terms of voltage.



RA-3977-24

FIG. 3 MICROWAVE SYSTEM FOR AUTOMATIC MEASUREMENT OF ATTENUATION AND PHASE SHIFT

The attenuation is measured by the drop in the level of  $V_2$ . The results for phase as a function of voltage are shown in Fig. 4. Since the loop gain is finite, the ability of the control system to drive  $E_1 - E_2$  to a null depends to some degree upon the levels of the signals along Paths A and B. As the attenuation in Path A is increased, the value of  $V_1$  for a given  $\phi$  varies somewhat. This variation is illustrated in Fig. 4 for 0, 6, and 10 db attenuation.

If the 0-db calibration curve were used when there was actually 6 db of attenuation, the inferred phase would be in error by about 6 degrees. In fact, up to 15 db attenuation the calibration curves shift about 1 degree/db of attenuation. Of course, the attenuation is measured

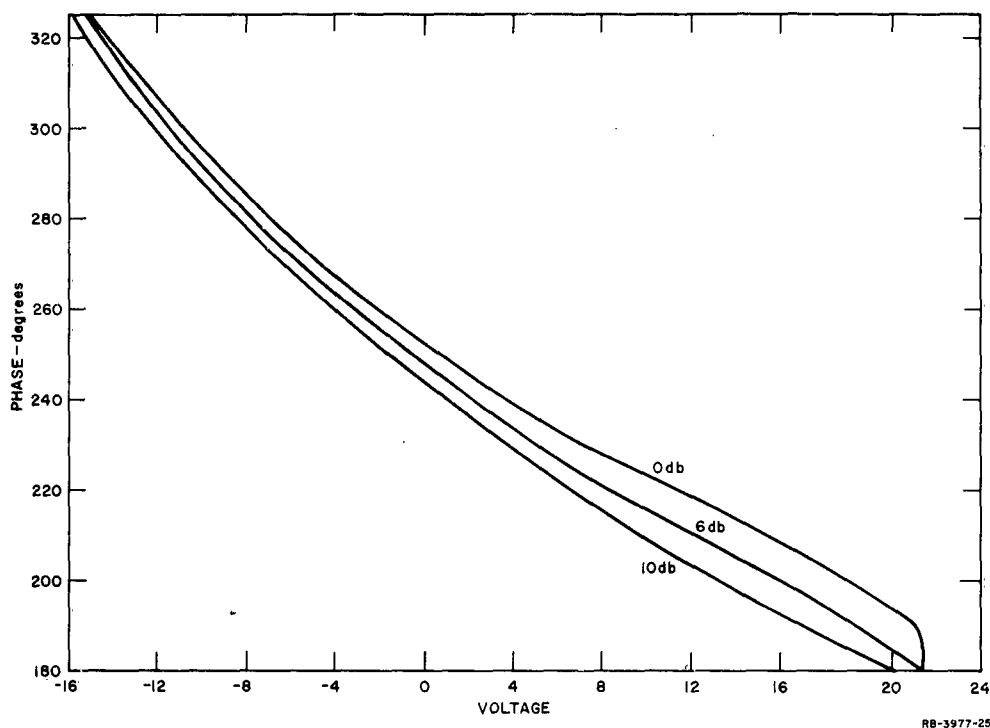
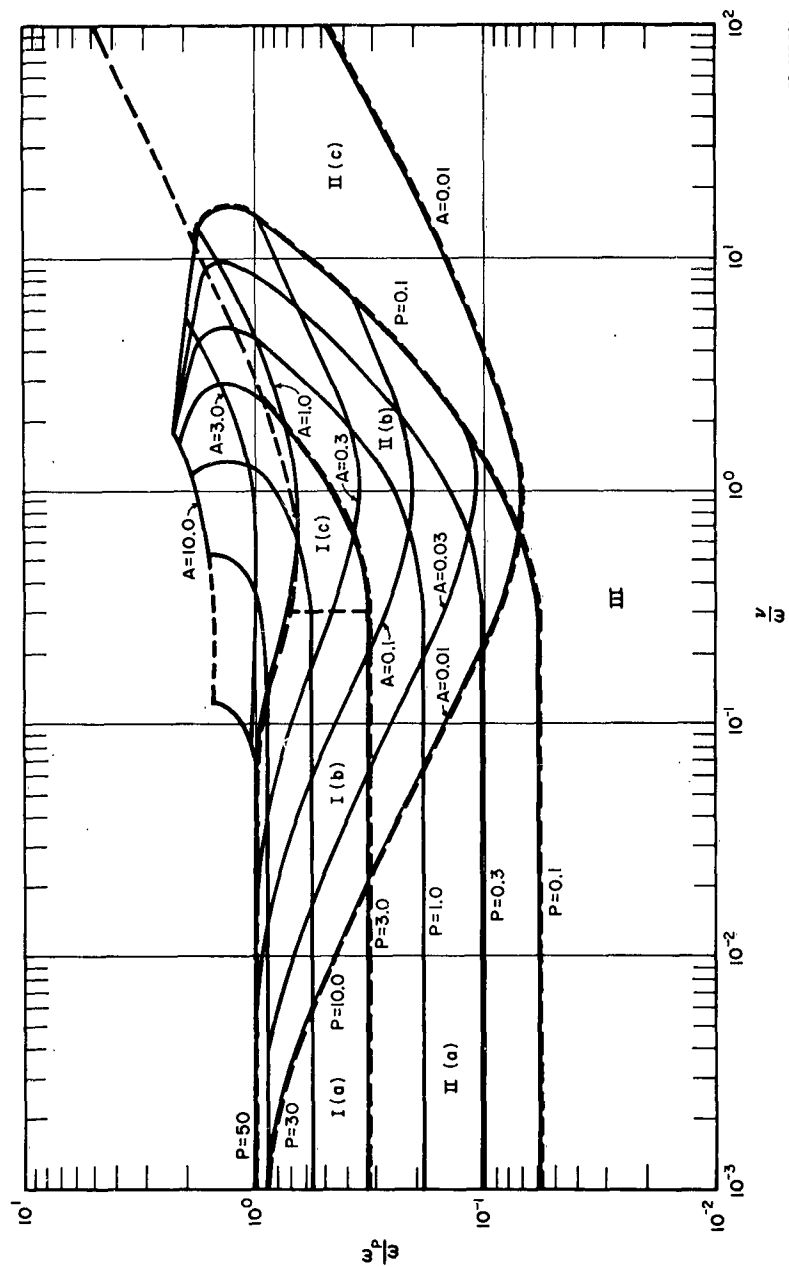


FIG. 4 PHASE AS A FUNCTION OF CONTROL VOLTAGE FOR THE AUTOMATIC SYSTEM ( $\Delta L = 3$  meters)

simultaneously so that the shift in calibration curve can be corrected for. Even so, when the plasma produces changes in Path A that are greater than 1 degree/db the shift would be negligible.

The range of plasma parameters for which the plasma produces 10 degrees/db can be found from Fig. 5. This chart is useful for microwave diagnostic problems. It presents the normalized plasma parameters in terms of the measured parameters, attenuation and phase shift, normalized to the electrical length of the plasma.  $P$  is the normalized phase shift in degrees per radian of path length.  $A$  is the normalized attenuation in db per radian. When  $P = 10A$ , the plasma will produce 10 degrees/db for any plasma length. From the chart it can be determined

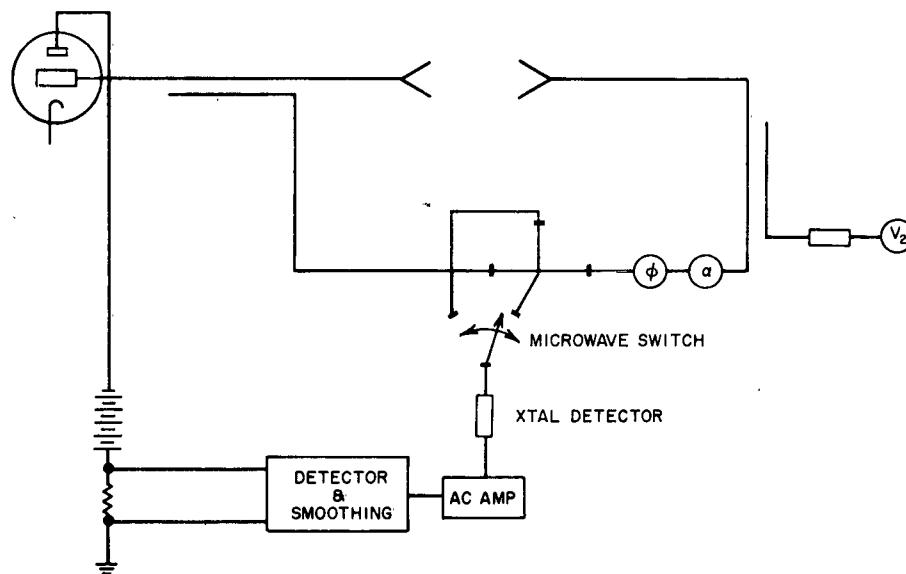


RB-657,581-1

FIG. 5 PLOT OF RATIO OF PLASMA TO WAVE FREQUENCY AND RATIO OF COLLISION TO WAVE FREQUENCY AS A FUNCTION OF NORMALIZED ATTENUATION IN db/radian AND NORMALIZED PHASE SHIFT IN deg/radian

that  $P > 10A$  for  $Z < 0.6$  for all  $\omega_p/\omega$  up to about 0.75. Thus, plasma parameters that are to the left of the  $Z = 0.6$  line will give accurate readings with this phase-measuring instrument, without correction for attenuation.

The time response of this instrument is limited by the bandwidth of the dc amplifier (about 50 cycles). Although wider-band dc amplifiers could be used they are costly. Wideband ac amplifiers are more easily available. Thus, if we could generate an error signal as an ac signal, amplify it through an ac amplifier, and detect and smooth the output before applying it to the reflector, we could increase the bandwidth of the system. This could be done by introducing a microwave switch so that  $E_1$  and  $E_2$  were sampled periodically. If they were different, an ac signal would result. If they were equal, the ac signal would be zero. Such a system is sketched in Fig. 6.



RA-3977-22

FIG. 6 AUTOMATIC SYSTEM USING ac AMPLIFIERS

This system would also have the advantage of eliminating the need for matched crystal detectors. The detection is by a single crystal detector. This could be an important consideration if the system were to be used to measure large attenuations, since it may be difficult to get crystals that are matched over a wide range of signal levels.

One other problem that has not been mentioned is that when the reflector voltage is varied, the power output changes. This can amount to several decibels for large frequency shifts. If the attenuation is small, this could mask the true value of the attenuation. In order to eliminate this error the servo loop could be periodically opened. Under this condition the klystron would be transmitting at the same frequency and with the same power output regardless of the plasma shift. However, this error is less than the 1 degree/db due to the servo system, so that if that error is tolerable this effect will be negligible for measurements of phase shift.

## TECHNICAL REPORTS IN THIS SERIES

### Reports Issued on Contract AF 19(122)-78

1. "Electric Dipoles in the Presence of Elliptic and Circular Cylinders," by W. S. Lucke, September 1949.
2. "Asymmetrically Fed Antennas," by C. T. Tai, November 1949.
3. "Double Fed and Coupled Antennas," by C. T. Tai, February 1949.
4. "Equivalent Radii of Thin Cylindrical Antennas with Arbitrary Cross Sections," by Carson Flammer, March 1950.
5. "Use of Complementary Slots in Aircraft Antenna Impedance Measurements," by J. T. Bolljahn, February 1950.
6. "Wing-Cap and Tail-Cap Aircraft Antennas," by J. V. N. Granger, March 1950.
7. "Investigation of Current Distribution on Asymmetrically-Fed Antennas by Means of Complementary Slots," by R. M. Hatch, Jr., February 1950.
8. "Electromagnetic Resonance Phenomena in Aircraft Structures," by A. S. Dunbar, May 1950.
9. "The Effect of a Grounded Slab on the Radiation from a Line Source," by C. T. Tai, June 1950.
10. "A Method for the Calculation of Progressive-Phase Antennas for Shaped Beams," by A. S. Dunbar, June 1950.
11. "Admittance of an Open-Ended Coaxial Line in an Infinite Grounded Plane," by W. S. Lucke, June 1950.
12. "A Variational Solution to the Problem of Cylindrical Antennas," by C. T. Tai, August 1950.
13. "Uniform Progressive-Phase Antennas Having Asymmetrical Amplitude Distributions," by A. S. Dunbar, September 1950.
14. "Small Dipole-Type Antennas," by J. T. Bolljahn, September 1950.
15. "Tables of Modified Cosine Integrals," January 1951.
16. "Prolate Spheroidal Wave Functions," by Carson Flammer, February 1951.

17. "An Antenna Evaluation Method," by W. S. Lucke, April 1951.
18. "Radar Response from Thin Wires," by C. T. Tai, March 1951.
19. "The Measurement of Low-Frequency Aircraft Antenna Properties Using Electrostatic Methods," by J. T. Bolljahn, September 1951.
20. (Dropped)
21. "A Method for the Calculation of Progressive-Phase Antennas for Shaped Beams," Part II, by A. S. Dunbar, May 1951.
22. "The Prolate Spheroidal Monopole Antenna," by Carson Flammer, August 1957, issued on Contract AF 19(604)-1296.
23. "Variational Solution for the Problem of the Asymmetric Dipole," by I. Reese, August 1951.
24. "Quasi-Static Solution for Diffraction of a Plane Electromagnetic Wave by a Small Oblate Spheroid," by C. T. Tai, September 1952 [Issued on Contract AF 19(604)-266].
25. "Transmission Through a Rectangular Aperture in an Infinite Screen," by W. S. Lucke, September 1951.

Reports Issued on Contract AF 19(604)-266

26. "Improvements in Instrumentation for the Investigation of Aircraft Antenna Radiation Patterns by Means of Scale Models," by R. M. Hatch, Jr., August 1952.
27. "The Vector Wave Solution of the Diffraction of Electromagnetic Waves by Circular Disks and Apertures," by Carson Flammer, September 1952.
28. "An Investigation of the Distribution of Current on Collinear Parasitic Antenna Elements," by R. M. Hatch, Jr., August 1952.
29. "On the Theory of Diffraction of Electromagnetic Waves by a Sphere," by C. T. Tai, October 1952.
30. "High-Frequency Airborne Direction Finding," by P. S. Carter, Jr., December 1952.
31. "An Electrolytic Tank Method for Low-Frequency Loop Antennas Studies," by R. F. Reese, July 1953.
32. "Radiation from a Uniform Circular Loop Antenna in the Presence of a Sphere," by C. T. Tai, December 1952.

33. "A Computer for Use with Antenna Model Ranges," by C. E. Fisher, February 1953.
34. "Tail-Cap Antenna Radiation Pattern Studies," by J. H. Bryan, January 1953.
35. "U-H-F Tail-Cap Antenna Pattern Characteristics and Their Control," by A. R. Ellis, March 1955 [issued on Contract AF 19(604)-1296].
36. "Mutual Admittance of Slots in Cylinders," by W. S. Lucke, February 1953.
37. "Radio Interference from Corona Discharges," by R. L. Tanner, April 1953.
38. "Effects of Airframe Configuration on Low-Frequency Antenna Characteristics," by C. M. Hoblitzell, April 1953.
39. "The Effects of Thin Resistive Coatings on Low-Frequency Aircraft Antenna Performance," by C. W. Steele [issued on Contract AF 19(604)-1296] January 1956.
40. "Analysis of the Overstation Behavior of Airborne ADF Systems," by H. H. Ward, June 1954.
41. "Some Electromagnetic Problems Involving a Sphere," by C. T. Tai, April 1953.
42. "Radiation Pattern Measurements of Stub and Slot Antennas on Spheres and Cylinders," by J. Bain, April 1953.
43. "Current Distribution on Wing-Cap and Tail-Cap Antennas," by Irene C. Carswell, May 1954.
44. "A Study of Radiating Structures for Perpendicularly-Polarized Flush Radar Antennas," by Edward M. T. Jones and Seymour B. Cohn, July 1953.
45. "Radiation from Current Elements and Apertures in the Presence of a Perfectly Conducting Half-Plane Sheet," by C. T. Tai, July 1954.
46. "A Glossary of Dyadic Green's Functions," by C. T. Tai, July 1954.
47. "Horizontally Polarized Long-Slot Array," by R. C. Honey, August 1954.

Reports Issued on Contract AF 19(604)-1296

48. "Microwave Radiation from Large Finite Bodies," by Seymour B. Cohn and Tetsu Morita, January 1955.

49. "Radiation from Electric and Magnetic Dipoles in the Presence of a Conducting Circular Disk," by Carson Flammer, February 1955.
50. "A Study of Some Inherent Errors in the Three-Dimensional Raydist System," by Irene Carswell, March 1955.
51. "Operating Characteristics of Flush-Mounted Bombing Antennas," by E. M. T. Jones, November 1955.
52. "Properties of the Asymmetric Dipole," by Irene Carswell, December 1955.
53. "Notch Coupling to the Electromagnetic Resonance of a Delta-Wing Aircraft," by William L. Jones, December 1955.
54. "A Flush-Mounted Horizontally Polarized Directional Antenna," by R. C. Honey, January 1956.
55. "Radiation from a Flush-Mounted Scanning Antenna on the Nose Section of a Supersonic Aircraft," by J. K. Shimizu and T. Morita, December 1955.
56. "An Economical Logarithmic Recording System," by Lloyd A. Robinson, June 1956.
57. "Variational Formulae for Domain Functionals in Electromagnetic Theory," by Carson Flammer, March 1957.
58. "Systems Considerations for High Speed Missile Seeker Antennas," by Donald L. Margerum and E. Thomas Brandon, May 1957. Confidential.
59. "High-Strength Dielectric Materials for Very Fast Aircraft," by Henry J. Sang, March 1957.
60. "Impedance Matching Limitations with Application to the Broadband Antenna Problem," by Arthur Vassiliadis, January 1957.
61. "Shunt-Fed and Notch-Fed Aircraft Antennas," by Robert L. Tanner, July 1957.
62. "A Study of Precipitation-Static Noise Generation in Aircraft Canopy Antennas," by Joseph E. Nanevich, September 1957.
63. "Electromagnetic Wave Propagation in a Medium with Variable Dielectric Constant  $1 + kr^{-1}$ ," by Carson Flammer, January 1958.

Reports Issued on Contract AF 19(604)-3458

64. "The Back-Scattering Cross Sections of Missile Trails," by Carson Flammer, June 1958.

65. "Ray-Tracing and Diffraction in a Medium with Variable Permittivity and Attenuation," by James A. Cochran, October 1958.
66. "Feasibility Study of Aircraft Antennas for Forward-Scatter and Meteor-Burst Communication," by J. F. Cline, July 1959.
67. "A Study of Possibilities for Improving Space Utilization and Performance of Rhombic Antennas," by Angel Martin-Caloto, July 1959.
68. "Aerodynamic Characteristics of Trailing-Wire Antennas at Supersonic Speeds," by F. B. Harris, Jr., March 1960.
69. "Voltage Breakdown of Antennas at High Altitudes," by W. E. Scharfman and T. Morita, April 1960.
70. "A Study of Corona Discharge Noise in Aircraft Antennas," by A. Vassiliadis, August 1960.
71. "Theoretical Limitations on the Broadbanding Potential of Antennas, with Application to Cavity Backed Slots and Other Antennas," by A. Vassiliadis and R. L. Tanner, August 1960.
72. "A New Approach to the Evaluation of HF Aircraft Antennas," by J. F. Cline, March 1961.
73. "Precipitation Charging and Corona-Generated Interference in Aircraft," by R. L. Tanner and J. E. Nanevicz, May 1961.
74. "Transmission Through an Ionized Medium in the Presence of a Strong Magnetic Field," by H. S. Rothman and T. Morita.

Reports Issued on Contract AF 19(628)-325

75. "One-Sided Multipactor Discharge Modes," by E. F. Vance and J. E. Nanevicz.

<p>AF Cambridge Research Laboratories, Bedford, Mass. AN AUTOMATIC SYSTEM FOR MEASURING PLASMA PARAMETERS, by W. E. Scharfman, May 1963, 14 pp. AFCRU-63-155 Unclassified Report</p> <p>An inexpensive system for automatic measurement of microwave phase shift is described. The system requires for its construction only components that would be required if a manual system were used, plus a servo loop. The phase is controlled by controlling the reflector voltage on a klystron, which in turn controls the microwave frequency. A description is given of a prototype system that was constructed and tested. Measured results of phase shift as a function of control voltage and attenuation are presented.</p>	<p>UNCLASSIFIED</p> <p>1. Microwaves 2. Plasmas</p> <p>I Stanford Research Institute, Menlo Park California II Scharfman, W. E. III Contract AF 19(628)-325 Project 4600, Task 460001</p>	<p>AF Cambridge Research Laboratories, Bedford, Mass. AN AUTOMATIC SYSTEM FOR MEASURING PLASMA PARAMETERS, by W. E. Scharfman, May 1963, 14 pp. AFCRU-63-155 Unclassified Report</p> <p>An expensive system for automatic measurement of microwave phase shift is described. The system requires for its construction only components that would be required if a manual system were used, plus a servo loop. The phase is controlled by controlling the reflector voltage on a klystron, which in turn controls the microwave frequency. A description is given of a prototype system that was constructed and tested. Measured results of phase shift as a function of control voltage and attenuation are presented.</p>	<p>UNCLASSIFIED</p> <p>1. Microwaves 2. Plasmas</p> <p>I Stanford Research Institute, Menlo Park California II Scharfman, W. E. III Contract AF 19(628)-325 Project 4600, Task 460001</p>	<p>UNCLASSIFIED</p> <p>1. Microwaves 2. Plasmas</p> <p>I Stanford Research Institute, Menlo Park California II Scharfman, W. E. III Contract AF 19(628)-325 Project 4600, Task 460001</p>
<p>AF Cambridge Research Laboratories, Bedford, Mass. AN AUTOMATIC SYSTEM FOR MEASURING PLASMA PARAMETERS, by W. E. Scharfman, May 1963, 14 pp. AFCRU-63-155 Unclassified Report</p> <p>An inexpensive system for automatic measurement of microwave phase shift is described. The system requires for its construction only components that would be required if a manual system were used, plus a servo loop. The phase is controlled by controlling the reflector voltage on a klystron, which in turn controls the microwave frequency. A description is given of a prototype system that was constructed and tested. Measured results of phase shift as a function of control voltage and attenuation are presented.</p>	<p>UNCLASSIFIED</p> <p>1. Microwaves 2. Plasmas</p> <p>I Stanford Research Institute, Menlo Park California II Scharfman, W. E. III Contract AF 19(628)-325 Project 4600, Task 460001</p>	<p>AF Cambridge Research Laboratories, Bedford, Mass. AN AUTOMATIC SYSTEM FOR MEASURING PLASMA PARAMETERS, by W. E. Scharfman, May 1963, 14 pp. AFCRU-63-155 Unclassified Report</p> <p>An expensive system for automatic measurement of microwave phase shift is described. The system requires for its construction only components that would be required if a manual system were used, plus a servo loop. The phase is controlled by controlling the reflector voltage on a klystron, which in turn controls the microwave frequency. A description is given of a prototype system that was constructed and tested. Measured results of phase shift as a function of control voltage and attenuation are presented.</p>	<p>UNCLASSIFIED</p> <p>1. Microwaves 2. Plasmas</p> <p>I Stanford Research Institute, Menlo Park California II Scharfman, W. E. III Contract AF 19(628)-325 Project 4600, Task 460001</p>	<p>UNCLASSIFIED</p> <p>1. Microwaves 2. Plasmas</p> <p>I Stanford Research Institute, Menlo Park California II Scharfman, W. E. III Contract AF 19(628)-325 Project 4600, Task 460001</p>

STANFORD  
RESEARCH  
INSTITUTE

MENLO PARK  
CALIFORNIA

## Regional Offices and Laboratories

Southern California Laboratories  
820 Mission Street  
South Pasadena, California

Washington Office  
808 17th Street, N.W.  
Washington 6, D.C.

New York Office  
270 Park Avenue, Room 1770  
New York 17, New York

Detroit Office  
1025 East Maple Road  
Birmingham, Michigan

European Office  
Pelikanstrasse 37  
Zurich 1, Switzerland

Japan Office  
911 Iino Building  
22, 2-chome, Uchisaiwai-cho, Chiyoda-ku  
Tokyo, Japan

## Representatives

Honolulu, Hawaii  
1125 Ala Moana Blvd.  
Honolulu, Hawaii

London, England  
19, Upper Brook Street  
London, W. 1, England

Milan, Italy  
Via Macedonio Melloni, 49  
Milano, Italy

Toronto, Ontario, Canada  
Room 710, 67 Yonge St.  
Toronto, Ontario, Canada